Misa Hayashida

List of Publications by Year
in descending order

26	203	1307594 7	1125743 13
papers	citations	h-index	g-index

26	26	26	197
all docs	docs citations	times ranked	citing authors

#	Article	IF	Citations
1	High-Energy Electron Scattering in Thick Samples Evaluated by Bright-Field Transmission Electron Microscopy, Energy-Filtering Transmission Electron Microscopy, and Electron Tomography. Microscopy and Microanalysis, 2022, 28, 659-671.	0.4	5
2	Higher-order structure of barley chromosomes observed by electron tomography. Micron, 2022, 160, 103328.	2.2	2
3	Phase plates in the transmission electron microscope: operating principles and applications. Microscopy (Oxford, England), 2021, 70, 75-115.	1.5	24
4	Nanoparticle size and 3D shape measurement by electron tomography: An Inter-Laboratory Comparison. Micron, 2021, 140, 102956.	2.2	4
5	Chromosome inner structure investigation by electron tomography and electron diffraction in a transmission electron microscope. Chromosome Research, 2021, 29, 63-80.	2.2	2
6	Higher-Order Structure of Human Chromosomes Observed by Electron Diffraction and Electron Tomography. Microscopy and Microanalysis, 2021, 27, 149-155.	0.4	7
7	Toward the quantitative the interpretation of hole-free phase plate images in a transmission electron microscope.. Ultramicroscopy, 2020, 209, 112875.	1.9	5
8	Higher-order Structure of Human Chromosomes Observed by Electron Tomography and Electron Diffraction. Microscopy and Microanalysis, 2020, 26, 656-659.	0.4	2
9	3D observation of chromosome scaffold structure using a 360Â° electron tomography sample holder. Micron, 2019, 126, 102736.	2.2	8
10	Parameters affecting the accuracy of nanoparticle shape and size measurement in 3D. Micron, 2019, 123, 102680.	2.2	12
11	Hole free phase plate tomography for materials sciences samples. Micron, 2019, 116, 54-60.	2.2	8
12	Thermal expansion coefficient measurement from electron diffraction of amorphous films in a TEM. Ultramicroscopy, 2018, 188, 8-12.	1.9	8
13	Evaluation of electron tomography reconstruction methods for interface roughness measurement. Microscopy Research and Technique, 2018, 81, 515-519.	2.2	5
14	Hole Free Phase Plate Electron Tomography in Material Sciences. Microscopy and Microanalysis, 2018, 24, 2224-2225.	0.4	2
15	Toward Quantitative Bright Field TEM Imaging of Ultra Thin Samples. Microscopy and Microanalysis, 2018, 24, 1612-1613.	0.4	3
16	Wavelet transform-based electron tomography measurement of buried interface roughness. Ultramicroscopy, 2018, 194, 64-77.	1.9	3
17	Computer simulations analysis for determining the polarity of charge generated by high energy electron irradiation of a thin film. Micron, 2017, 100, 10-22.	2.2	16
18	Practical electron tomography guide: Recent progress and future opportunities. Micron, 2016, 91, 49-74.	2.2	31

#	Article	IF	Citations
19	High-accuracy electron tomography of semiconductor devices. Microscopy and Microanalysis, 2015, 21, 1609-1610.	0.4	2
20	Tomographic measurement of buried interface roughness. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2015, 33, 040605.	1.2	3
21	Three dimensional accurate morphology measurements of polystyrene standard particles on silicon substrate by electron tomography. Micron, 2015, 79, 53-58.	2.2	7
22	Accurate measurement of relative tilt and azimuth angles in electron tomography: A comparison of fiducial marker method with electron diffraction. Review of Scientific Instruments, 2014, 85, 083704.	1.3	7
23	Nano-dot markers for electron tomography formed by electron beam-induced deposition: Nanoparticle agglomerates application. Ultramicroscopy, 2014, 144, 50-57.	1.9	19
24	Nano-Dot Markers for Electron Tomography Formed by Electron Beam-Induced Deposition: Nanoparticle Agglomerates Application. Microscopy and Microanalysis, 2014, 20, 782-783.	0.4	1
25	Calibration method of tilt and azimuth angles for alignment of TEM tomographic tilt series. Review of Scientific Instruments, 2011, 82, 103706.	1.3	6
26	Automatic coarse-alignment for TEM tilt series of rod-shaped specimens collected with a full angular range. Micron, 2010, 41, 540-545.	2.2	11